

# PAG/TFUG Meeting

## Student Presentations, San Jose State University

November 13, 2018

### Meeting Hosts and Sponsors

**Presentation competition awards sponsored by:**

**UC Components, Inc.:**

1st Place Group: \$25 Gift Card for each student

2nd Place Group: \$20 Gift Card for each student

3rd Place Group: \$10 Gift Card for each student



***NCCAUS:***

**Top 3** Place Groups: One year AVS Student Membership for each student



Northern California Chapter of the American Vacuum Society

**User Groups**

**Hosted by:**

**SJSU Chapter of Society  
of Plastic Engineers and  
SJSU Material  
Advantage**

**&**

**Fall 2018 MatE 232  
Course (Instructor:  
Michael Oye), Plasma  
Processing of  
Materials (Dept. of  
Chemical and Materials  
Engineering, SJSU)**

# Tentative Agenda

- **5:30 pm: Dinner**
- **6:00 pm: Introduction and Welcome**
- **6:05 pm: Student Presentations**
  - **Using Paschen curves to determine DC plasma sputtering conditions**, Calvin Chen, Dirar Mashaleh, Corey Abraham, Abdul Kikhia
  - **Achieving high aspect ratio deep trench etching**, Dylan Benjamin, Aditya Dhaketa, Alexander Cress, Briana Fees, Gautam Pisharody
  - **Managing particle formation in plasmas**, Curtis Ma, Samuel Yeung, Simran Singh, Michael Walker, Muhammad Tariq, Charleston Chua
  - **Ensuring substrate uniformity at the edges of the substrate in large diameter processing tools**, Zachary Rayha, Harjeet Hansi, Stephanie Villavicencio, Yanghyeon Kim
  - **Designing gas injection systems and showerhead design for uniform plasma deposition**; Andy Giang, Raul Gonzalez, Yifu Chen
  - **Using diagnostic instruments to develop the next generation of plasma etch/dep tools**; Artem Biryukov, Riley Foss, John Scheckel, Janaye Marshall, Crystal Pereira, Zhe Mi
- **7:00 pm: Industry Presentations: Lucia Feng, Vladimir Kudriavtsev**
- **7:40 pm: Panel Discussion**
- **8:30 pm: Awards presentation, meeting adjourn, and networking reception**